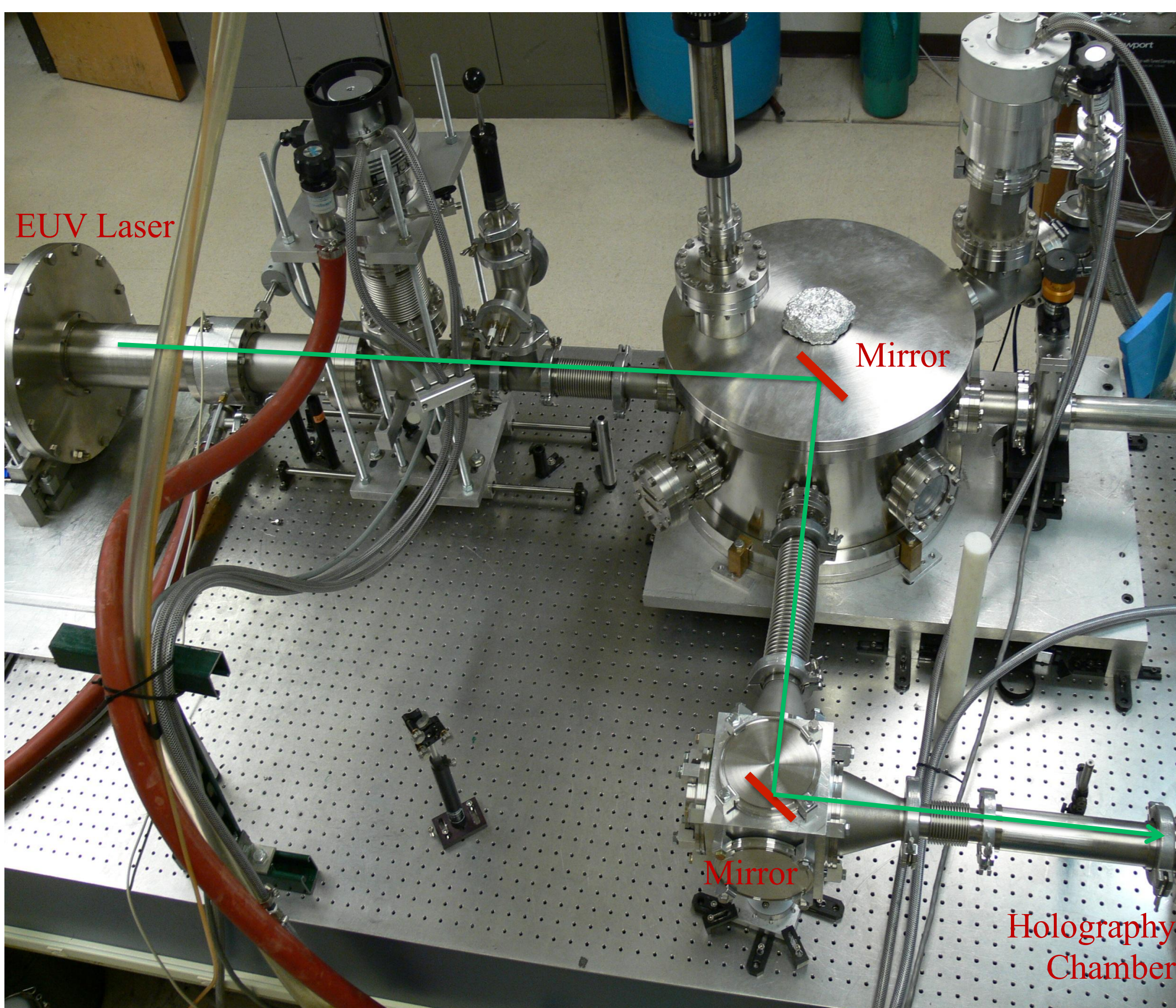
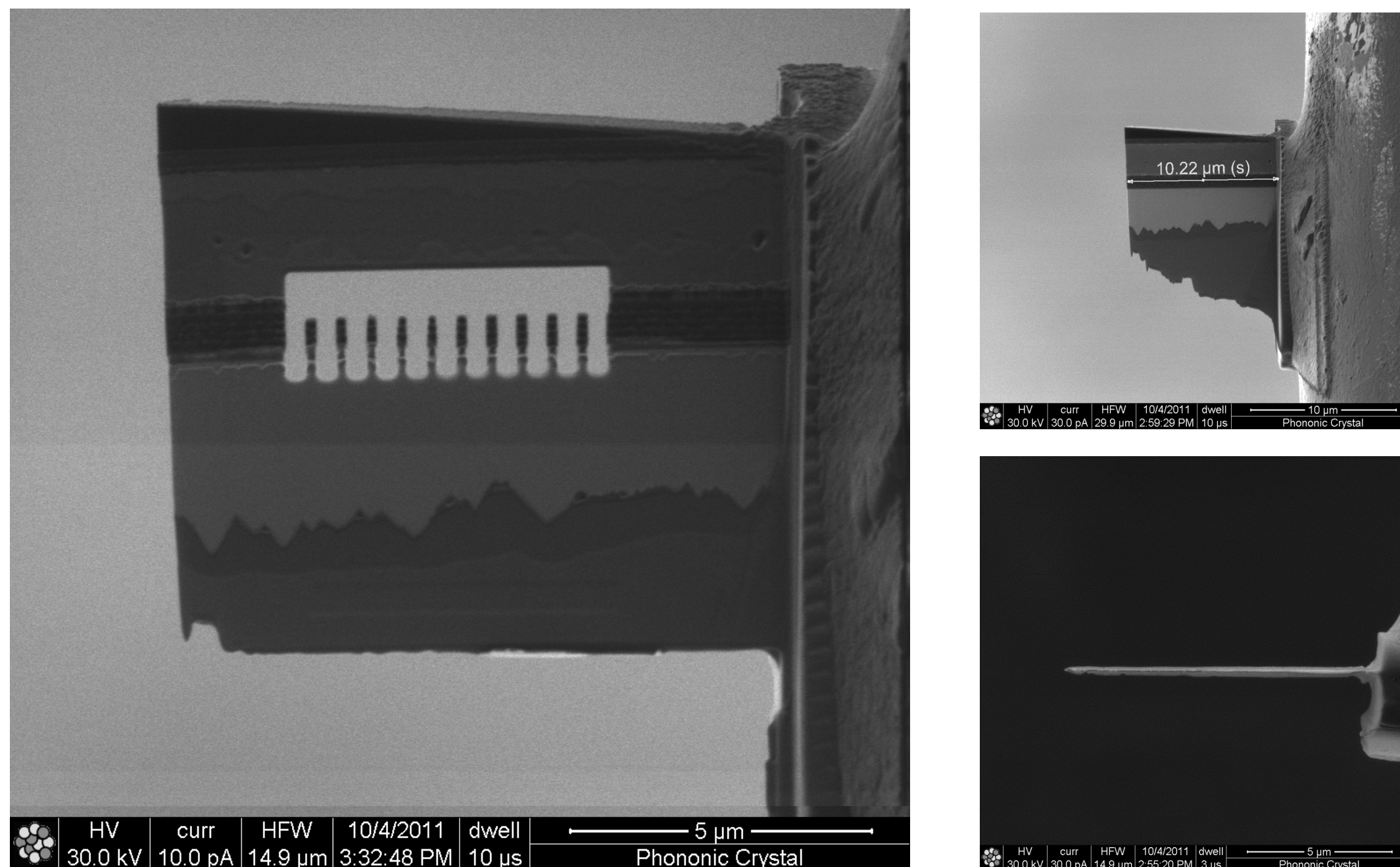


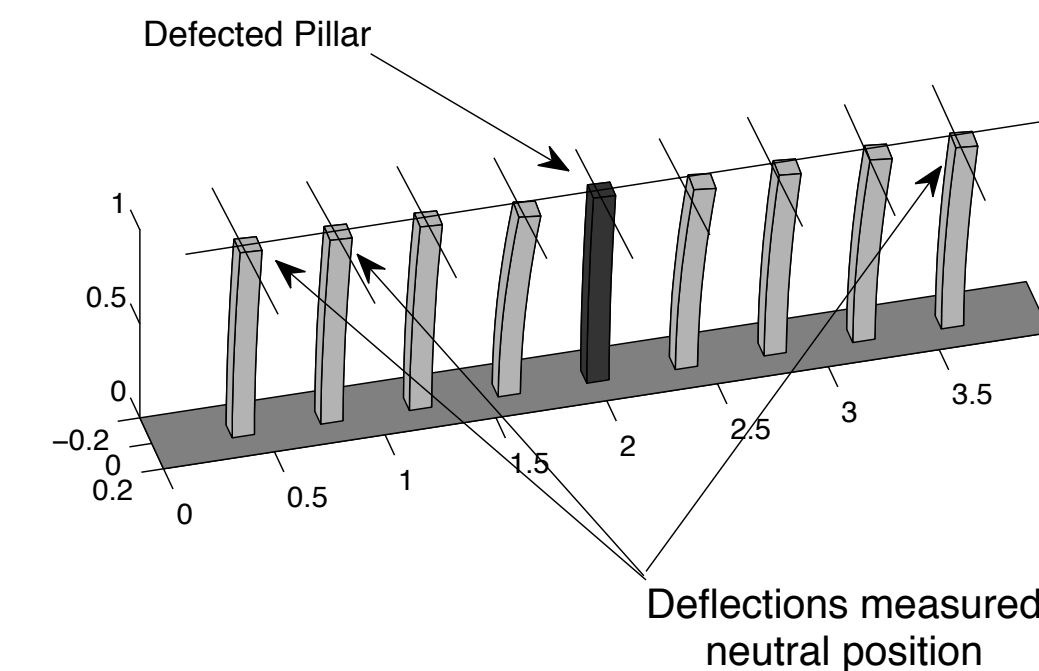
Motivation

- Single Molecule Detection.
- Monitor amplitude envelope of array
- Intrinsic Localized Modes (ILMs) pin to defect locations.
- Molecule attaches to a pillar in the array -- shape of entire envelope will change.
- Use Fourier Transform Holography via EUV laser for real-time imaging.
- Use Gallium Arsenide (GaAs) crystals with square lattice.



Simulation

- Hamiltonian for the system of oscillators gives rise to the equations of motion.
- Potential energy functional is:



$$E_{pot} = E_2 + E_4$$

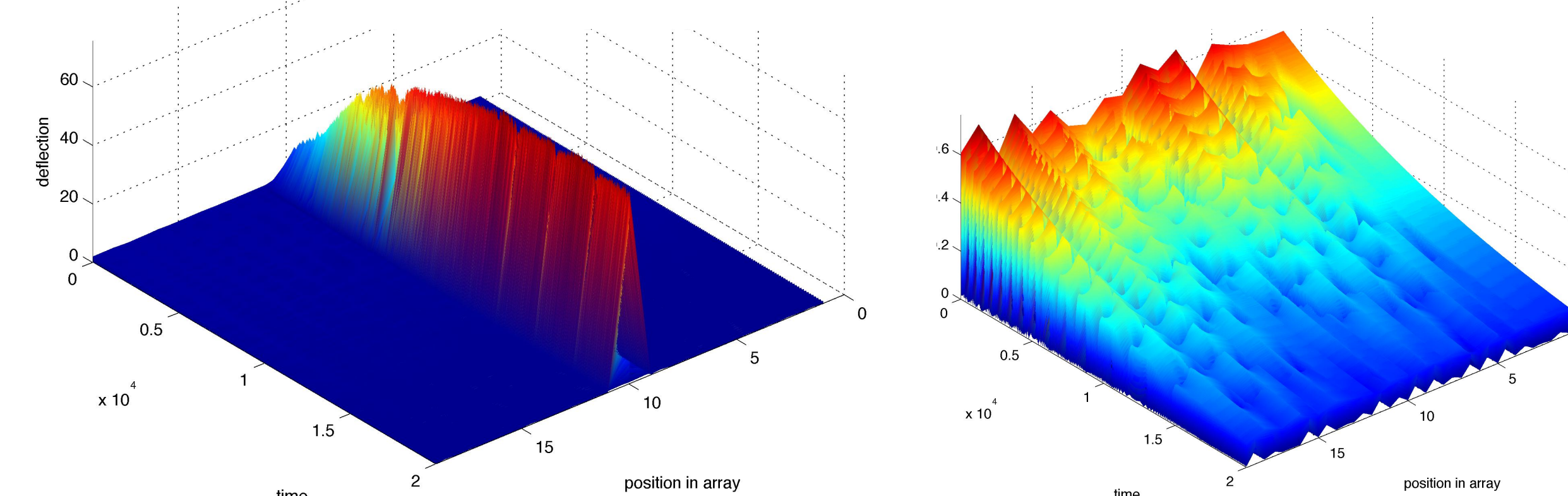
$$E_2 = \frac{1}{2} \sum_k \alpha_{1,x} u_{k,x}^2 + \alpha_{1,y} u_{k,y}^2 + \alpha_{2,x} (u_{k,x} - u_{k-1,x})^2 + \alpha_{2,y} (u_{k,y} - u_{k-1,y})^2 + \alpha_{3,y} (u_{k,x} - u_{k,y})^2$$

$$E_4 = \frac{1}{4} \sum_k \beta_{1,x} u_{k,x}^4 + \beta_{1,y} u_{k,y}^4 + \beta_{2,x} (u_{k,x} - u_{k-1,x})^4 + \beta_{2,y} (u_{k,y} - u_{k-1,y})^4 + \beta_{3,x} (u_{k,x} - u_{k,y})^4$$

$$\ddot{u}_{x,n} = -\frac{\partial E}{\partial u_{x,n}} + \text{friction} + \text{forcing} \quad \ddot{u}_{y,n} = -\frac{\partial E}{\partial u_{y,n}} + \text{friction} + \text{forcing}$$

Intrinsic Localized Modes

- ILM: special oscillatory mode which concentrates energy at one location in an array
- ILMs also 'pin' to defects in an array.
- Form of the entire array's vibration changes upon defect



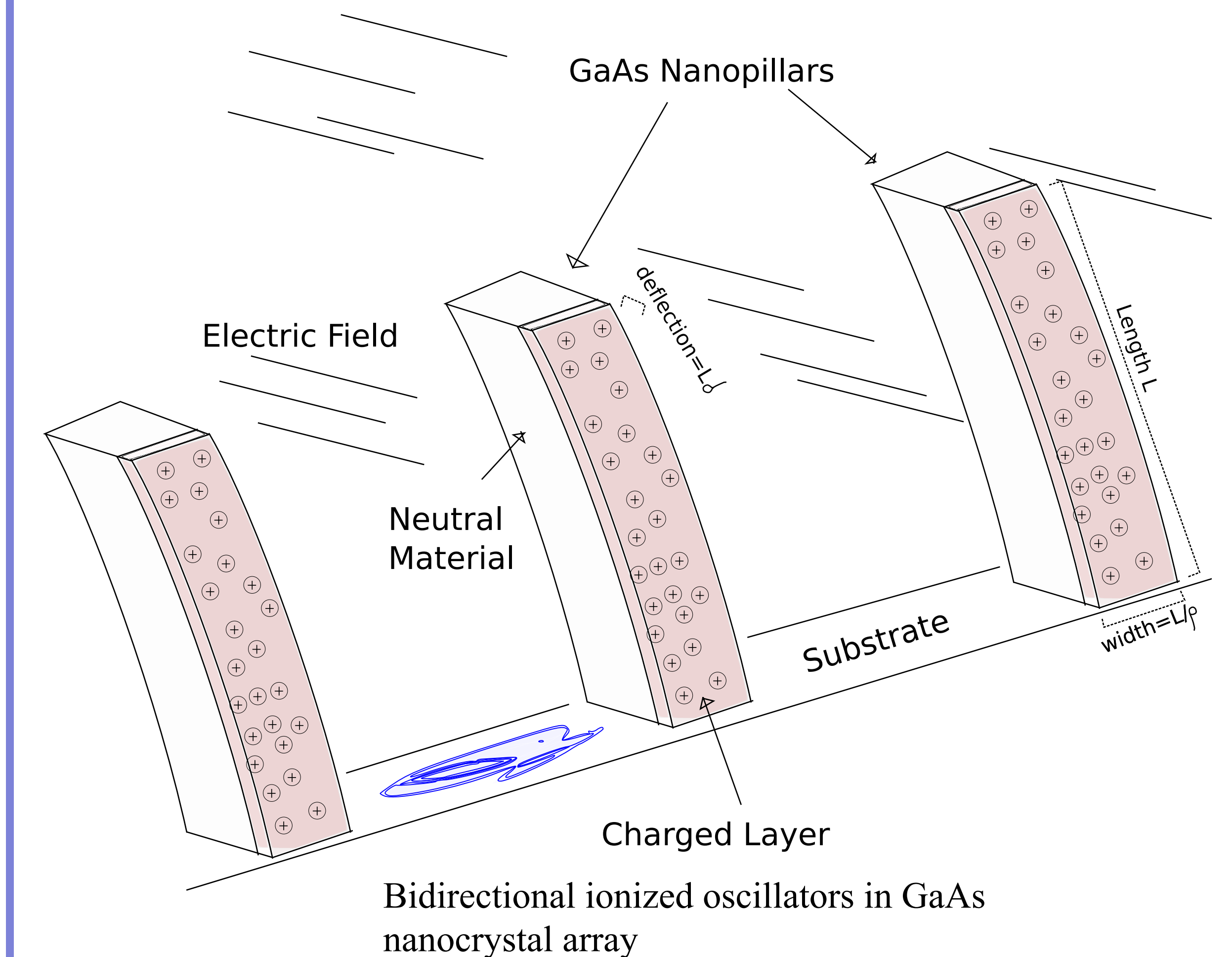
Left: x-direction of vibration
Right: y-direction

Acknowledgement

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ILM Excitement

- Create Charged layer on one side of pillars
- Shoot ion beam at pillars
- Drive pillar array with electric field
- Breakdown Field of GaAs is $\sim 4 \times 10^7$ V/m



- Length of pillars = L [nm]
- Ratio length:width = k [dimensionless]
- Deflection = u [nm]
- Max deflection = $L\delta$ [nm] (δ is percent)

- Strength of field needed:

$$E_{field} = \frac{\delta}{k^3} \cdot 4.65 \times 10^{11} \text{ V/m}$$

Deflection percent δ	Aspect ratio k	Electric field E
0.01	40	73.20 KV/m
0.01	100	4.65 KV/m
0.005	100	2.32 KV/m